	SMART MATERIALS AND STRUCTURES				
PREREQUIS	ITES CATEGORY	L	Τ	Р	С
	PE	3	0	0	3
COURSE OB.	JECTIVES:				
	dge of smart materials and structures is essential designing mechanical s	-			
Ū.	ring applications, the course aims at training students in smart mate	rials	and	struc	ture
applicat	ion and analysis				
		0	0	0	0
UNIT I	STRUCTURES Structures, Potential Feasibility of Smart Structures, Key Elements of Smart Structures	9			9
	belectric materials, Properties, piezoelectric Constitutive Relations, Depoling and Co				
	ssis, Creep and Strain Rate effects, Inchworm Linear Motor. Beam Modeling: Beam				
	ts, Inchworm Linear Motor Beam Modeling with induced strain Actuation-single Ac				
Pure Extension,	Pure Bending harmonic excitation, Bernoulli-Euler beam Model, problems, Piezoelec	trical A	pplica	ations	•
UNIT II	SHAPE MEMORY ALLOY	9	0	0	9
	nenomenology, Shape Memory Effect, Phase Transformation, Tanaka's Constitutive				
Wires, Vibration	Control through SMA, Multiplexing. Applications Of SMA and Problems. ER and M Fluid Composition and behavior, The Bingham Plastic and Related Models, Pre-Yiel	A Post	lids: N	lecha Post	nism Vial
	s in Clatches, Dampers and Others.	u Kesj	Jonse.	1 051-	
UNIT III	VIBRATION ABSORBERS	9	0	0	9
series and Para		-	-		-
	l Ilel Damped Vibrations (OverView), Active Vibration Absorbers, Fiber Optics Sensors, Fiber Optics in Crack Detection, applications. Control of Structures: Modeling	, Phys	ical F	heno	mena
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3.	Piezoelectric Actuators and Wtrasonic Motors - K. Uchino, Kluwer Academic Publishers, Boston, 1997 (ISBN: 0792398114).
4.	Handbook of Giant Magnetostrictive Materials - G. Engdahl, Academic Press, San Diego, Calif.; London, 2000 (ISBN: 012238640X).
5.	Shape Memory Materials - K. Otsuka and C. M. Wayman, Cambridge University Press, Cambridge; New York, 199~ (ISBN: 052144487X).

COUR Upon o	Bloom Taxonomy Mapped			
<i>CO1</i>	Understand the behavior and applicability of various smart materials	Understand		
<i>CO2</i>	Design simple models for smart structures & materials	Create		
<i>CO3</i>	Perform simulations of smart structures & materials application	Analyse		
<i>CO4</i>	Conduct experiments to verify the predictions	Analyze		

COURSE ARTICULATION MATRIX															
COs/POs	PO1	PO2	PO3	PO4	PO5	PO6	PO7	PO8	PO9	PO10	PO11	PO12	PSO1	PSO2	PSO3
CO1	2	2	1	1	2	0	0	0	0	0	0	0	2	2	0
CO2	2	2	1	1	2	0	0	0	0	0	0	0	2	2	0
CO3	2	2	1	1	2	0	0	0	0	0	0	0	2	2	0
CO4	2	2	1	1	2	0	0	0	0	0	0	0	2	2	0
Avg	2	2	1	1	2	0	0	0	0	0	0	0	2	2	0
	3/2/1 – indicates strength of correlation (3 – high, 2- medium, 1- low)														